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Chi Fai Benny Cheung
Suet Sandy To
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Introduction

On behalf of the Organizing Committee, we would like to present the proceedings of the Sixth Asia Pacific Conference on Optics Manufacture. The First Asia Pacific Conference on Optics Manufacture (APCOM 2007) was held in Hong Kong, then Taipei, Changchun, Guangzhou, and Shanghai. The sixth conference returned to Hong Kong and was organized by the State Key Laboratory of Ultraprecision Machining Technology (SKL of UMT) of The Hong Kong Polytechnic University. The SKL of UMT has been actively engaging in cutting-edge research in design, manufacturing, and measurement of freeform optical elements.

The conference is one of the fastest growing regions in terms of economics, education, and technology. We were so glad to witness that the number of scientists, engineers, and academics, as well as research institutes and companies involved in advanced optics manufacture has grown tremendously as compared with that ten years ago. The applications of optical components and products in various industries has become more widespread. There has also been significant advancement of technologies for design, manufacturing, and measurement of the optical elements and systems. The theme of this conference continues to provide an excellent opportunity and platform for academics and industries to discuss and exchange ideas and their research findings, while also enabling them to acquire knowledge of the latest developments of optics-related technologies.

We invited international well-known experts from different countries such as Australia, China, Germany, Singapore, the United Kingdom, United States, etc., to deliver keynote speeches and invited talks and companies supporting our conference to showcase their latest research achievements, technologies, and products.

We would like to express our sincere thanks to the co-organizers and sponsors for their support of the organization of the conference. We would also like to express our sincere thanks to K.C. Wong Foundation which provided financial support for the conference. I hope that all of you enjoyed the event, and that the spirit of collaboration among us will continue in the years to come.

Chi Fai Benny Cheung

